



# IUMRS-ICEM 2018

AUGUST 19(SUN.) - 24(FRI.), 2018 / DAEJEON, KOREA

<b>Session Title</b>	<b>Deposition and modification methods for carbon materials</b>	<b>Session Code</b>	<b>Th-G2</b>
<b>Date and Time</b>	<b>2018-08-23 / 13:30 - 15:30</b>		
<b>Place</b>	<b>Room G</b>		
<b>Session Chair</b>	<b>TBA</b>		

Th-G2-1

13:30 - 14:00

### **[Invited] Functional Modification of Graphene**

Martin Kalbac<sup>1</sup>, Petr Kovaricek<sup>1</sup>, Zdenek Bastl<sup>1</sup>, Karolina Drogowska<sup>1</sup>, Zuzana Malnikova-Kominkova<sup>1</sup>, Michaela Fridrichova<sup>1</sup>, Timotheus Verhagen<sup>2</sup>, and Jana Vejpravova<sup>2</sup>

<sup>1</sup>J. Heyrovsky Inst. of Physical Chemistry, Czech, <sup>2</sup>Charles Univ., Czech

Th-G2-2

14:00 - 14:30

### **[Keynote] New Methods for Direct Growth of Graphene on Insulator ~ Paper, Pencil, Carbon Dioxide ~**

Satoru Kaneko<sup>1</sup>, Shigeo Yasuhara<sup>2</sup>, Tamio Endo<sup>3</sup>, Rieko Sudo<sup>3</sup>, Takashi Tokumasu<sup>4</sup>, Kazuo Satoh<sup>5</sup>, Masahito Kurouchi<sup>1</sup>, Manabu Yasui<sup>1</sup>, Takeshi Rachi<sup>1</sup>, Satomi Tanaka<sup>1</sup>, Chihiro Kato<sup>1</sup>, Akifumi Matsuda<sup>6</sup>, Mamoru Yoshimoto<sup>6</sup>, and Hirifumi Takikawa<sup>7</sup>

<sup>1</sup>Kanagawa Inst. of Industrial Sci. and Tech., Japan, <sup>2</sup>Japan Advanced Chemicals, Japan, <sup>3</sup>Sagamihara Surface Laboratory., Japan, <sup>4</sup>Tohoku Univ., Japan, <sup>5</sup>Osaka Research Inst. of Industrial Sci. and Tech., Japan, <sup>6</sup>Tokyo Inst. of Tech., Japan, <sup>7</sup>Toyohashi Univ.

Th-G2-3

14:30 - 15:00

### **[Invited] Self-Supporting ta-C Film Consisting of Laminated Layers Prepared using T-shape Filtered Arc Deposition**

Toru Harigai<sup>1</sup>, Masafumi Yamano<sup>1</sup>, Yuki Kondo<sup>1</sup>, Fuminori Yoda<sup>1</sup>, Satoshi Degai<sup>1</sup>, Tsuyoshi Tanimoto<sup>1</sup>, Yoshiyuki Suda<sup>1</sup>, Hirofumi Takikawa<sup>1</sup>, Mamiko Nishiuchi<sup>2</sup>, Hironao Sakaki<sup>2</sup>, Kiminori Kondo<sup>2</sup>, Satoru Kaneko<sup>3</sup>, and Shinsuke Kunitsugu<sup>4</sup>

<sup>1</sup>Toyohashi Univ. of Tech., Japan, <sup>2</sup>Nat'l Inst. for Quantum and Radiological Sci. and Tech., Japan, <sup>3</sup>Kanagawa Inst. of Industrial Sci. and Tech., Japan, <sup>4</sup>Industrial Tech. Center of Okayama Prefecture, Japan